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PATENT

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## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Fukuda et al. ) Group Art Unit 1763  
Appl. No. : 09/511,934 )  
Filed : February 24, 2000 )  
For : THIN-FILM FORMING )  
APPARATUS HAVING AN )  
AUTOMATIC CLEANING )  
FUNCTION FOR CLEANING )  
THE INSIDE )  
Examiner : R. Kackar )

RECEIVED  
SEP 25 2002  
TC 1700 MAIL ROOMAMENDMENT AFTER FINAL

Assistant Commissioner for Patents  
Washington, D.C. 20231

Dear Sir:

In response to the Office Action mailed July 1, 2002 (Paper number 8), please amend the above-captioned application as follows:

IN THE CLAIMS:

Please amend Claim 1 as follows:

1. (Twice amended) A thin film forming apparatus comprising:  
a reaction chamber for forming at a film formation temperature a thin film on a workpiece placed on a susceptor provided in the reaction chamber, said susceptor being made of aluminum nitride and provided with a heater for heating the workpiece, said reaction chamber being provided with a conveyor for loading and unloading the workpiece into and from the reaction chamber; and  
a cleaning device for cleaning unwanted deposits adhering to the inside of the reaction chamber at predetermined intervals, said cleaning device comprising: